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Compiled by Donald M. Mattox (4/26/2016)\*

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NOTE: Papers published in the proceedings of conferences may or may not reflect what was actually presented at the conference. Some proceedings publish papers as first submitted by the authors – others must go through a peer-review process where the paper may be changed significantly. The proceedings of the Society of Vacuum Coaters beginning in 2013 is unique in that the papers submitted (“original” – not peer reviewed papers) are published in the proceedings of the conference (bound and digital) while some of the papers are also submitted to Surface and Coating Technology (SCT) for peer review and possible publication in that journal. The papers that are published in SCT are indicated on the papers published in the SVC Proceedings.

#### Appendix 1

##### **\*Proceedings of the International Conference on Metallurgical Coatings (ICMC)**

- Selected (peer reviewed) papers from the conferences were published in Thin Solid Films [Elsevier] until 1981 after which they were published in Thin Solid Films or Surface and Coating Technology [Elsevier] - A hard cover book format compilation of the peer reviewed papers was published at least through 2002.
- 1974 - Proceedings of Conference on Structure/Property Relations in Thick Films and Bulk Coatings, edited by R.C. Krutenat, published by AIP/AVS (1974); also J. Vac. Sci. Technol. 11(4) (1974)
- 1975 - Proceedings – 2<sup>nd</sup> Conference on Structure/Property Relations in Thick Films and Bulk Coatings, edited by R.C. Krutenat, published by AIP/AVS (1975); also J. Vac. Sci. Technol. 12(4) (1975)
- 1976 – Proceedings of the 3rd International Conference on Metallurgical Coatings (1976) edited by R.F. Bunshah also Thin Solid Films 39&40 (1976)
- 1977 – Proceedings of the 4th International Conference on Metallurgical Coatings and Thin Films (2 vols.) edited by R.F. Bunshah (*In the Preface Bunshah called this the 4th meeting even though the name ICMC didn't originate until 1976*) (1977)
- 1978 – Proceedings of the 5th International Conference on Metallurgical Coatings and Thin Films (2 vols.) - edited by R.F. Bunshah (1978)
- 1979 – Proceedings of the 6th International Conference on Metallurgical Coatings and Thin Films (2 vols.) - edited by J.N. Zemel (1979)
- 1980 - Proceedings of the 7th International Conference on Metallurgical Coatings and Thin Films (2 vols.) – edited by J.N. Zemel (1980)



- 1981 – Proceedings of the 8th International Conference on Metallurgical Coatings and Thin Films (2 vols.) – edited by J.N. Zemel (1981)
- 1982 – Proceedings of the 9th International Conference on Metallurgical Coatings and Thin Films (4 vols.) – Vol.1-3 edited by J.N. Zemel, Vol. IV edited by R.C. Krutenat (1982)
- 1983 - Proceedings of the 10th International Conference on Metallurgical Coatings and Thin Films (1983)
- 1984 – Proceedings of the 11th International Conference on Metallurgical Coatings and Thin Films (2 vols.) edited by R.C. Krutenat and J. Zemel (1984)
- 1985 - Proceedings of the 12th International Conference on Metallurgical Coatings and Thin Films (1985)
- 1986 - Proceedings of the 13th International Conference on Metallurgical Coatings and Thin Films (1986)
- 1987 - Proceedings of the 14th International Conference on Metallurgical Coatings and Thin Films (4 vols.), edited by R.C. Krutenat (1987)
- 1988 – Proceedings of the 15th International Conference on Metallurgical Coatings and Thin Films (3 vols.) edited by R. C. Krutenat (1988)
- 1989 – Proceedings of the 16th International Conference on Metallurgical Coatings and Thin Films, edited by Bruce D. Sartwell (1989)
- 1990 – Proceedings of the 17th International Conference on Metallurgical Coatings and Thin Films, edited by B. D. Sartwell, J. N. Zemel, Gary McGuire, and G.E. Bresnock (1990)

**\*Proceedings of the International Conference on Metallurgical Coatings and Thin Films (ICMCTF) – continuation of ICMC bound books**

- 1991 – Proceedings of the 18th International Conference on Metallurgical Coatings and Thin Films, edited by Gary E. McGuire, D.C. McIntyre, and S. Hofmann (1991)
- 1992 – Proceedings of the 19th International Conference on Metallurgical Coatings and Thin Films, edited by Gary E. McGuire, B. D. Sartwell, and S. Hofmann (1992)
- 1993 - Proceedings of the 20th International Conference on Metallurgical Coatings and Thin Films (1993)
- 1994 - Proceedings of the 21st International Conference on Metallurgical Coatings and Thin Films, edited by G.E. McGuire, H.A. Jehn, and B.D. Sartwell - Surface & Coating Technology, Vols. 68/69 (1994)
- 1995 – Proceedings of the 22nd International Conference on Metallurgical Coatings and Thin Films (ICMCTF) - Surface & Coating Technology, Vols. 76/77 (1995)
- 1996 - Proceedings of the 23rd International Conference on Metallurgical Coatings and Thin Films (ICMCTF) - Surface & Coating Technology, Vols. 86/87 (1996)
- 1997 – Proceedings of the 24th International Conference on Metallurgical Coatings and Thin Films (ICMCTF), - Surface & Coating Technology, Vols. 94/95 (1997)
- 1998 – Proceedings of the 25th International Conference on Metallurgical Coatings and Thin Films (ICMCTF), edited by S. Mitterer, S. Rohde, J.H. Givens, and B.D. Sartwell - Surface & Coating Technology, Vol. 108-109 (1998)
- 1999 - Proceedings of the 26th International Conference on Metallurgical Coatings and Thin Films (ICMCTF) (2 vols.) edited by A. Matthews, J.H. Givens, W.L. Ensinger, and S.L. Rohde - Surface & Coating Technology, Vols. 120-121 (1999)
- 2000 - Proceedings of the 27th International Conference on Metallurgical Coatings and Thin

- Films, edited by Bruce D. Sartwell, Whittler, Wahl, and Alberto Pique (2000)
- 2001 - Proceedings of the 28th International Conference on Metallurgical Coatings and Thin Films (2001)
- 2002 – Proceedings of the 29th International Conference on Metallurgical Coatings and Thin Films (2 Vols.) edited by Christian Mitterer, Alberto Pique, Krassimir Marchev, Jochen M. Schneider, and Andrey A. Voevodin (2002)
- 2003 - Proceedings of the 30th International Conference on Metallurgical Coatings and Thin Films (2003) – CD & soft bound?

\* Obviously the list is not complete and I could not verify some titles/authors/dates so caution is recommended if in doubt. Some books have many printing dates that should not be confused with the copy right date – used books sales often use the printing date, not the copyright date. Also some books have several editions and sometimes these may not be indicated in the book listing.

**Sources include:**

1. Library of Donald M. Mattox and Vivienne J. Harwood Mattox
2. AVS – Jefferson Lab Collection – book list [https://www.jlab.org/div\\_dept/cio/IR/AVS.html](https://www.jlab.org/div_dept/cio/IR/AVS.html)
3. IUVSTA Bibliography (Professor B. R. Kendall) – book list
4. AVS – List of textbooks on vacuum Science and Technology ([avs.org/Textbooks](http://avs.org/Textbooks))
5. Used and new books for sale - Amazon.com; Alibris-UK; Abe
6. Plus numerous individuals including: Todd Plaisted, Yuri Dymshits (Russian references), Martin Wust, Marcy Stutzman, Nigel Harris (UK), Guillaume Blanchard (France), Varga Gabor (Hungary) - whom I thank

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